

FIG. 1a
(PRIOR ART)

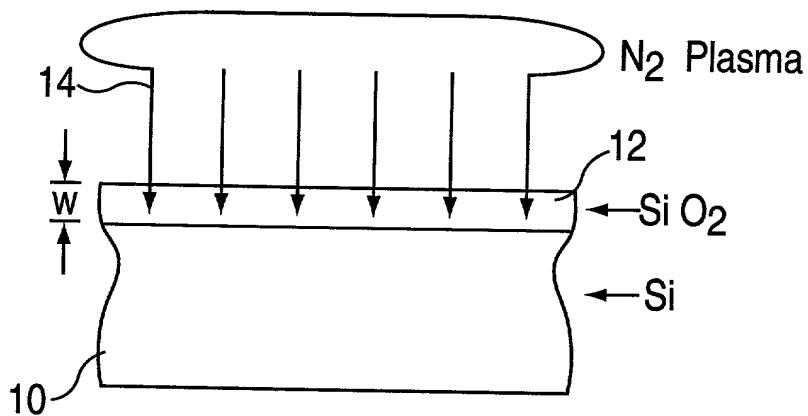


FIG. 1b
(PRIOR ART)

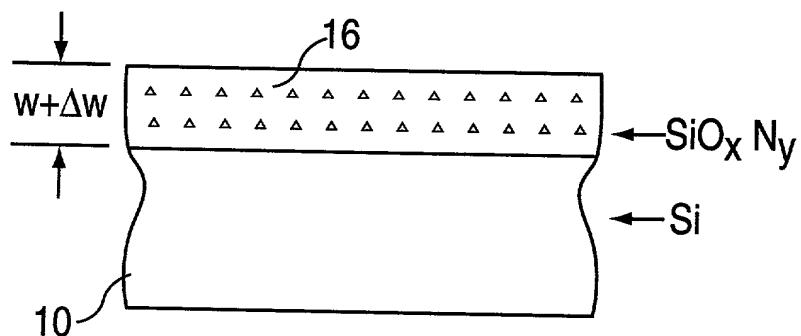


FIG. 1c
(PRIOR ART)

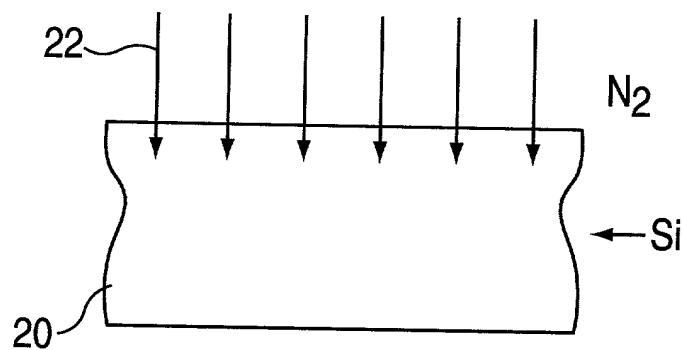


FIG. 2a

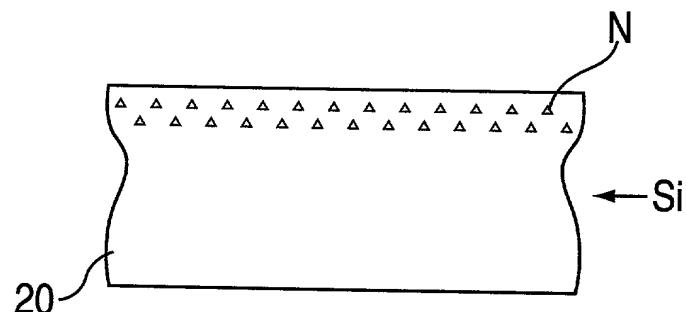


FIG. 2b

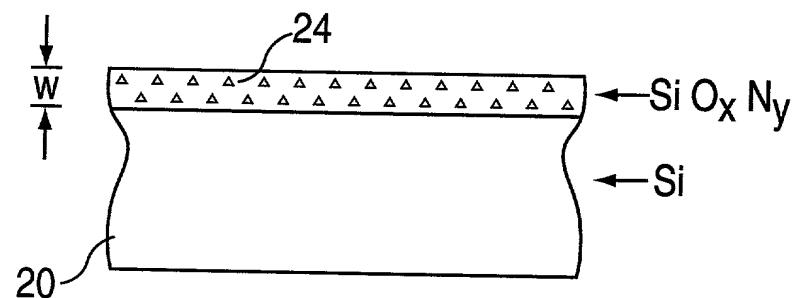


FIG. 2c

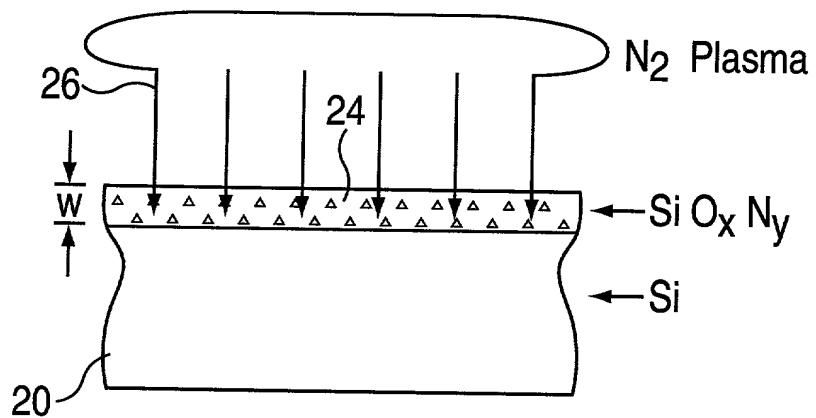


FIG. 2d

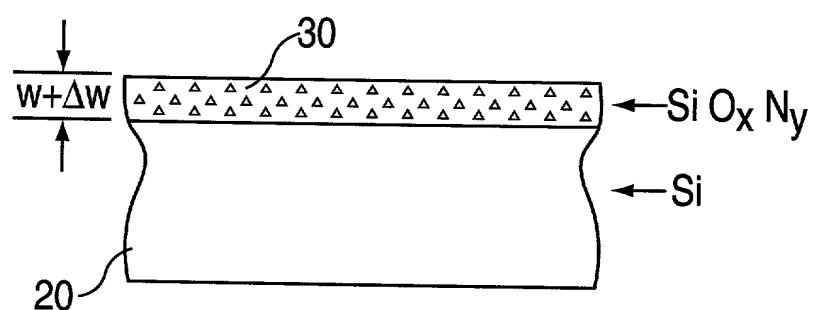


FIG. 2e

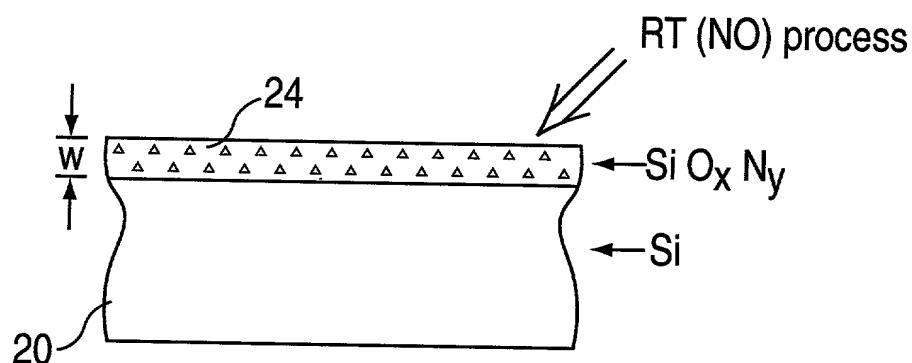


FIG. 3a

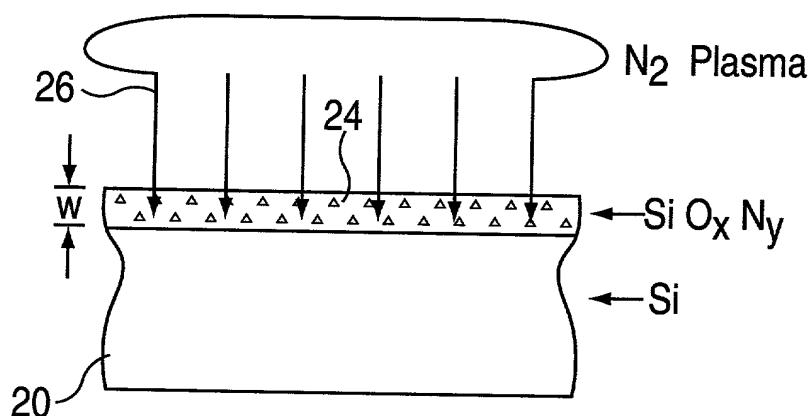


FIG. 3b

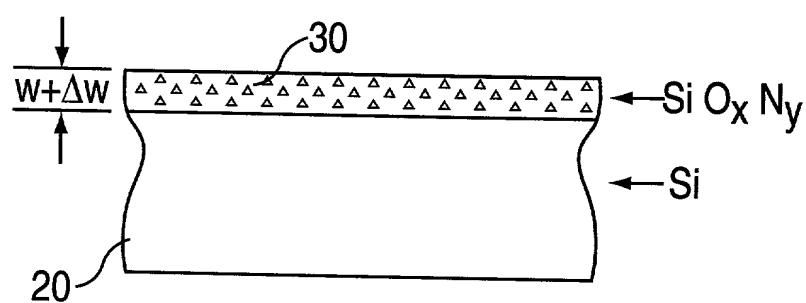


FIG. 3c

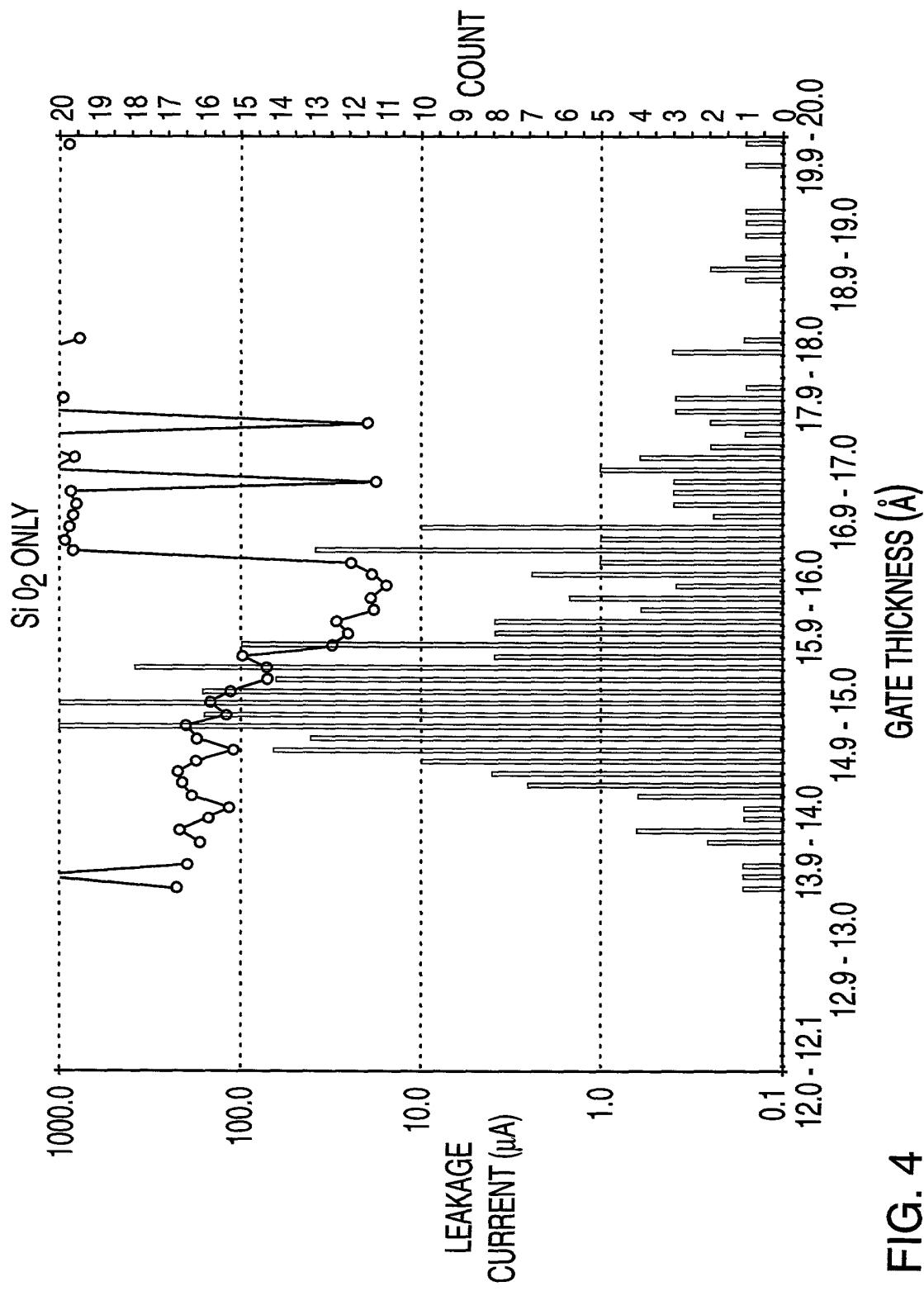


FIG. 4

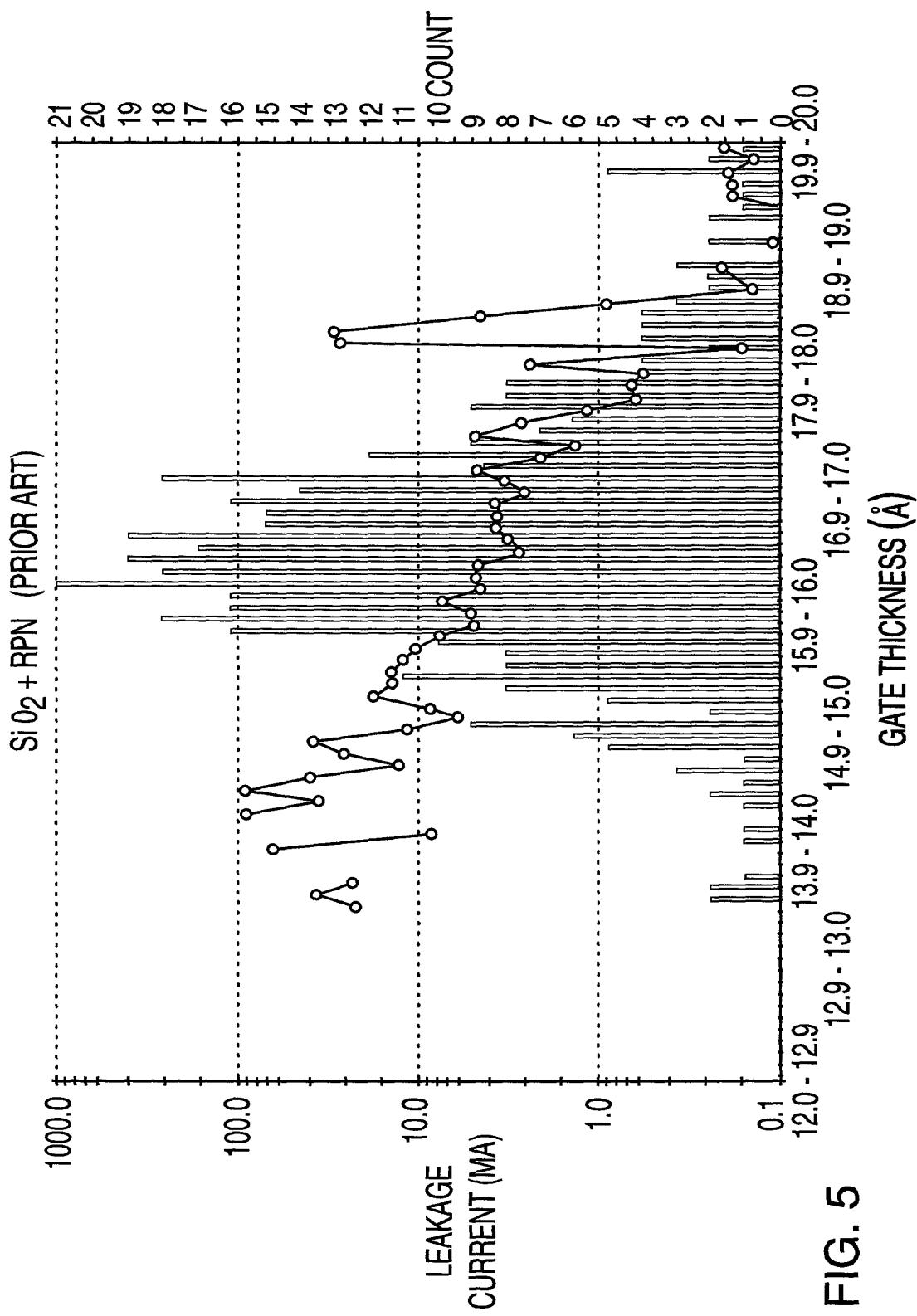
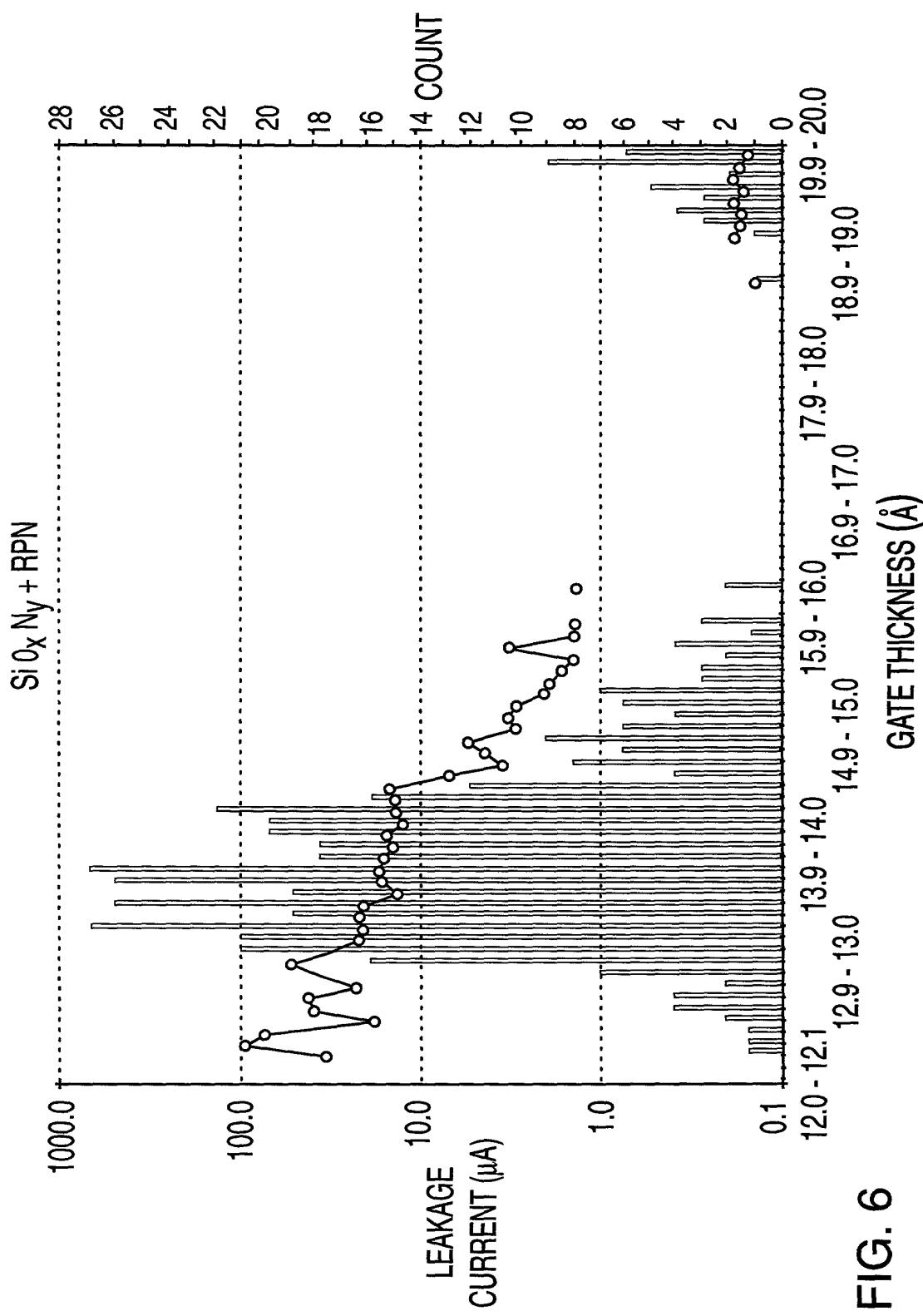


FIG. 5

**FIG. 6**

UNIFORMITY OF GATE FILM

	<u>MEAN THICKNESS (nm)</u>	<u>σ</u>
RPN of Si O ₂ (Dry)	1.74	0.287
RPN of Si O ₂ (Wet)	1.68	0.115
RTNO	1.70	0.0293
RTNO +RPN@ 550°C	1.74	0.0246
RTNO +RPN@ 750°C	1.73	0.0296

FIG. 7

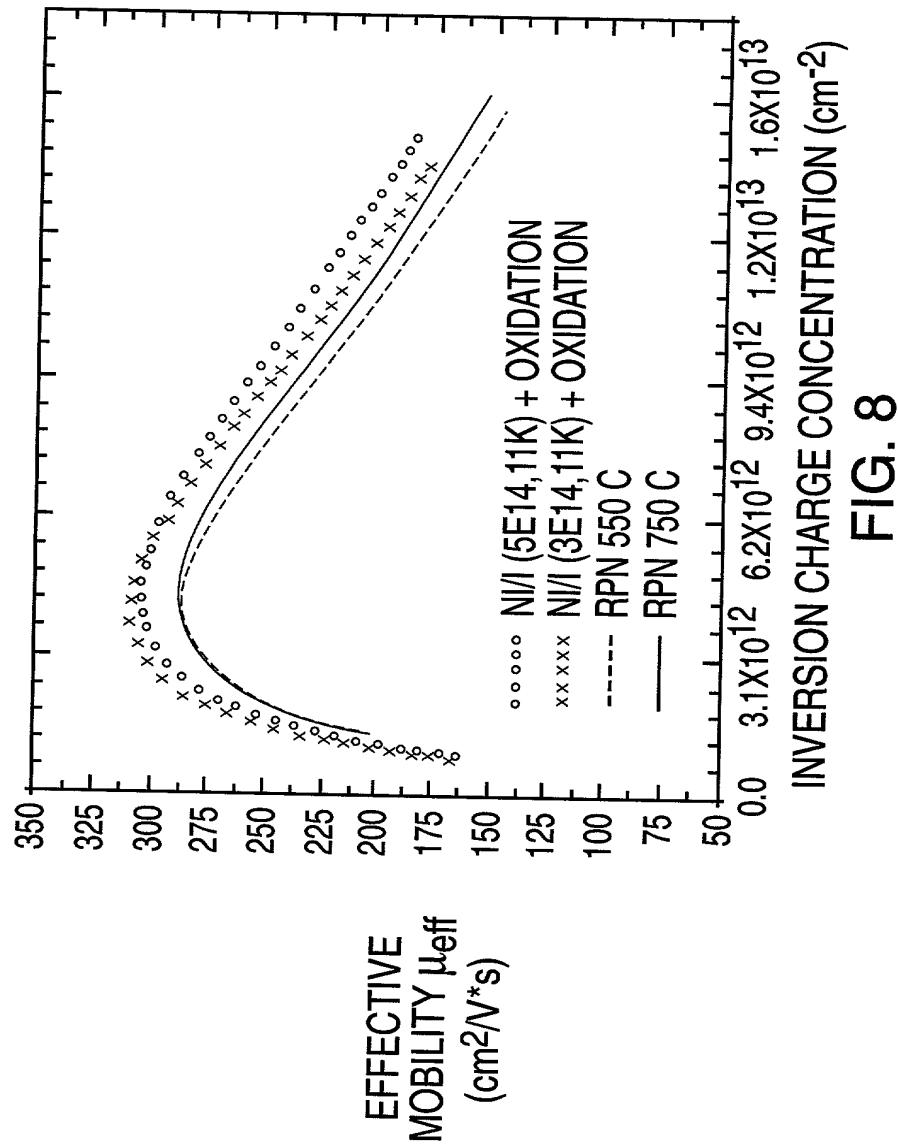


FIG. 8